

## Intersubband quantum-box lasers: An update

D. Botez, D. Xu, M. D'Souza, G. Tsviid, J. C. Shin, A. Khandekar, T. Kuech,  
A. Lyakh and P. Zory  
*Univ. of Wisconsin-Madison and Univ. of Florida, U.S.A.*

Semiconductor lasers whose active region is composed of a 2D array of intersubband quantum boxes (IQBs) hold the promise<sup>1</sup> to be significantly more efficient and reliable than multi-stage intersubband lasers (i.e., quantum-cascade lasers). That is a direct consequence of the fact that the electron-relaxation times in deep, unipolar QBs are at least a factor of 20 times larger than in quantum wells, as experimentally confirmed by several groups.<sup>2</sup>

We have reported<sup>3</sup> on efficient 4.7  $\mu\text{m}$  emission from deep-well, GaAs-based single-stage devices. Electron-beam patterning and transfer to  $\text{SiO}_2$  has provided 33 nm-diameter disks on 80 nm centers, to be used as the mask for IQB fabrication via *in-situ* gas etching and regrowth in an MOCVD crystal-growth system.

Key issues related to the fabrication of IQBs have been addressed and resolved. We have achieved controlled *in-situ* etching and regrowth of high-crystalline-quality, high-resistivity GaAs in 40 nm-deep trenches. While intersubband-transition devices are by and large not affected by the presence of exposed surfaces, that is not the case at the nanoscale level, since Fermi-level pinning can lead to full depletion of the devices. Etch-and-regrowth experiments have been carried out on (110)-oriented GaAs substrates, which basically correspond to the IQB edges. Special treatment of dry-etched surfaces followed by *in-situ* gas etching and regrowth has led to the elimination of charge-trapping states at the interfaces, and thus to the elimination of Fermi-level pinning for the proposed IQB-device fabrication.

1. Chia-Fu Hsu, Jeong-Seok O, Peter Zory and Dan Botez, *IEEE J. Select. Topics Quantum Electron.* **6**, 491 (2000).
2. S. Sauvage, P. Boucaud, R. P. S. Lobo, F. Bras, G. Fishman, R. Prazeres, F. Glotin, J. M. Ortega and J.-M. Gerard, *Phys. Rev. Lett.* **88**, 177402 (2002).
3. D. P. Xu, A. Mirabedini, M. D'Souza, S. Li, D. Botez, A. Lyakh, Y.-J. Shen, P. Zory, and C. Gmachl, *Appl. Phys. Lett.* **85**, 4573 (2004).